

the plurality of cathodes and the plurality of insulating layers arranged in alternating layers;

wherein said plurality of cathodes are evaporated by vacuum arc discharge.

2. (Amended) The vacuum arc evaporation source of Claim 1, wherein said plurality of cathodes are disposed in coaxially alternating layers with insulating material.

5. (Amended) A film formation apparatus for forming a laminate film including a plurality of heterogeneous films on a surface of a substrate, the apparatus comprising:

a vacuum arc evaporation source having a plurality of cathodes, each made of different materials; and a plurality of insulating layers for insulating the plurality of cathodes from each other; the plurality of cathodes and the plurality of insulating layers arranged in alternating layers; wherein said plurality of cathodes are evaporated by vacuum arc discharge;

an arc power supply for supplying arc discharge power to said plurality of cathodes of said vacuum arc evaporation source; and

a switch for switching the arc discharge power of said arc power supply among the plurality of cathodes of said vacuum arc evaporation source.

6. (Amended) A film formation apparatus for forming a laminate film including a plurality of heterogeneous films on a surface of a substrate, the apparatus comprising:

a vacuum arc evaporation source having a plurality of cathodes, each made of different materials; and a plurality of insulating layers for insulating the plurality of cathodes from each other; the plurality of cathodes and the plurality of insulating layers arranged in alternating layers; wherein said plurality of cathodes are evaporated by vacuum arc discharge; and

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cont a magnetic filter for generating a magnetic field to curve plasma containing material from said vacuum arc evaporation source so as to remove coarse particles from the plasma and introduce the plasma into vicinity of the substrate.

5/23/07 8. (Amended) The film formation apparatus according to Claim 6, further comprising:

an arc power supply for supplying arc discharge power to the plurality of cathodes of said vacuum arc evaporation source; and

a switch for switching the arc discharge power of said arc power supply among the plurality of cathodes of said vacuum arc evaporation source.

A4 10. (Amended) The film formation apparatus according to Claim 5; further comprising:

a magnet disposed adjacent to a surface of the cathode opposite a surface on which plasma is generated, for controlling a motion of an arc point of the vacuum arc discharge.